Application No. 09/756,140 Art Unit 1755

May 21, 2004 Supplemental Reply to Office Action of August 26, 2003

AMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the present application.

Listing of Claims:

 (Currently Amended) An -besseive A polishing composition for metal comprising an oxidizing agent, water and a polymer particle having a functional group that traps a metal ion, wherein the functional group that traps a metal ion is improdiagetic soid.

2-4. (Canceled)

5. (Currently Ammadad) The absolute for motal poliching composition according to claim 1, wherein the particle waving a functional useup that trops a motal ion to a particle comprising an ion exchange-roots, and the average particle dispeter of the particle is 1.0 mm or legs.

6-7. (Canceled)

8. (Gurrently Amended) A process for producing the an abrasive for metal comprising a polymer particle having a functional group that traps a metal ion, wherein the functional group that traps a metal ion is iminodiacetic acid, according to claim 5, wherein the process comprises Application No. 09/756,140 Art Unit 1755

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wet-milling an ion exchange rount the polymer having a functional group that traps a metal ion.

- 9. (Currently Amended) a process for producing the an abrasive for metal comprising a polymer particle having a functional group that traps a metal ion, wherein the functional group that traps a metal ion is minodinectic acid, according to cloim 5, wherein the process comprises dry-milling and then wet-milling an ion overhampersector the polymer having a functional group that traps a metal ion.
 - 10. (Canceled)
- (Previously Presented) The abrasive for metal according to claim 1, wherein the metal is copper or copper alloy.
 - 12-13. (Canceled)
- 14. (Currently Amended) The polishing composition for metal according to claim 12 claim 1 wherein the oxidizing agent is hydrogen peroxide.

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- 15. (currently Amended) The polishing composition for metal according to claim abor 1, wherein the composition further comprises at least one selected from the group consisting of a spherical particle, bensorriazole and a bensorriazole derivative.
- 16. (Currently Amended) A process for polishing a metal by chemical mechanical polishing, wherein the process is conducted by using the polishing composition for metal according to claim \$2-1.
- (Previously Presented) The process according to claim 16, wherein the metal is copper or copper alloy.

18-19. (Canceled)